

ABSTRACT

[0283] A method of manufacturing an electron beam apparatus having an airtight container with electron-emitting devices contained therein and spacers provided in the airtight container comprising the coating step of providing a film on a spacer substrate to be the spacers, and characterized in that the coating step includes the applying step of applying liquid film material by emitting from an emitting portion in a predetermined direction to a part of a surface of the spacer substrate facing the emitting portion.

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